

**AMENDMENTS TO THE CLAIMS**

*Please amend the claims as follows:*

1. (CURRENTLY AMENDED) A vacuum deposition apparatus comprising:

a susceptor for heating a glass substrate, a portion of the susceptor providing an area used as a sliding portion on which to slide the glass substrate to a desired position;

lift pins for supporting the glass substrate;

a robot arm for transferring the glass substrate onto the susceptor and returning the glass substrate from the susceptor, wherein the robot arm slides the glass substrate on the sliding portion of the susceptor; and

a groove formed in said portion of the susceptor for receiving material resulting from sliding of the glass substrate by the robot arm on the surface of the susceptor.

2. (PREVIOUSLY PRESENTED) The vacuum deposition apparatus according to claim 1, wherein a length of said sliding portion, measured from said groove, is at least 3 mm.

3. (PREVIOUSLY PRESENTED) The vacuum deposition apparatus according to claim 2, wherein a length of said sliding portion, measured from said groove, is 10 mm.

4. (PREVIOUSLY PRESENTED) The vacuum deposition apparatus according to claim 1, wherein the susceptor is made of a quartz material.

5. (PREVIOUSLY PRESENTED) The vacuum deposition apparatus according to claim 1, wherein the section of said groove formed in said portion of the susceptor has a polygonal configuration.

6. (PREVIOUSLY PRESENTED) The vacuum deposition apparatus according to claim 1, wherein the bottom face of the groove formed in said portion of the susceptor has a curved configuration.

7. (PREVIOUSLY PRESENTED) The vacuum deposition apparatus according to claim 1, wherein the bottom face of the groove formed in said portion of the susceptor includes an incline plane and a perpendicular plane.

8. (PREVIOUSLY PRESENTED) The vacuum deposition apparatus according to claim 1, wherein the groove formed in said portion of the susceptor has a V-shaped configuration.

9. (NEW) The vacuum deposition apparatus according to claim 1, wherein the lift pins directly support the glass substrate prior to the glass substrate being placed on a surface of the susceptor.

10. (NEW) The vacuum deposition apparatus according to claim 4, wherein the susceptor is in direct contact with the glass substrate when the glass substrate is heated.

11. (NEW) The vacuum deposition apparatus according to claim 1, wherein the robot arm inclines the glass substrate with respect to a surface of the sliding portion of the susceptor when sliding the glass substrate.

12. (NEW) The vacuum deposition apparatus according to claim 1, wherein the sliding portion of the susceptor comprises:

a first planar portion;

a second planar portion above the first planar portion,

wherein the groove is formed in the second planar portion, and

wherein the glass substrate slides on the second planar portion.

13. (NEW) A method to position a glass substrate in a vacuum deposition apparatus, comprising:

positioning the glass substrate above a susceptor;

lowering the glass substrate directly onto a plurality of lift pins of the susceptor, the susceptor having a sliding portion with a groove formed in the sliding portion;

retracting the plurality of lift pins to place the glass substrate directly on a surface of the susceptor; and

sliding the glass substrate onto the susceptor such that any film forming material collects in the groove of the sliding portion of the susceptor.

14. (NEW) The method of claim 13, further comprising inclining the glass substrate with respect to a surface of the sliding portion of the susceptor prior to the sliding the glass substrate onto the susceptor.